



Serial No. 09/843,023
Attorney Docket No. 40013-0002

2823

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application:
Becky Losee

Serial No.: 09/843,023

Filed: April 26, 2001

For: METHODS FOR ETCHING SILICON
TRENCHES

Confirmation No. 7229

Group Art Unit: 2823

Examiner: J. Maldonado

#12/Amending
Changes

3/11/03

Smith

Commissioner for Patents
Washington, D.C. 20231

Box Non-Final Response

Sir:

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AMENDMENT AND REQUEST FOR RECONSIDERATION
UNDER 37 C.F.R. §§ 1.111 & 1.115

In response to the Office Action dated November 21, 2002, Applicant requests reconsideration of this application in light of the following amendments and remarks.

03/12/2003 ASKITH 00000002 180013 09843023

01-FC:1203 04.00 CH
02-FC:1203 104.00 CH

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D. C. 20231, on this 21st day of February 2003.

Signed: _____

Dated: _____

Ken Horton
2/21/03

2/21/2003

IN THE TITLE

Please substitute the following Title for the originally filed Title. A copy of the title showing the amendment is attached as Appendix A.

METHODS FOR ETCHING DEEP SILICON TRENCHES WITH A HIGH
DEPTH UNIFORMITY